



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:)
NISHIMOTO et al) Art Unit: 2823
Serial No.: 08/897,839) Examiner: K. Eaton
Filed: July 21, 1997)
For: STRESS-ADJUSTED INSULATING)
FILM FORMING METHOD,)
SEMICONDUCTOR DEVICE AND)
METHOD OF MANUFACTURING THE)
SAME)

RECEIVED
AUG 11 2003
TECHNOLOGY CENTER 2800

RESPONSE TO OFFICE ACTION OF APRIL 7, 2003

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Responsive to the office action of April 7, 2003, please amend the captioned application as follows: